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(12) United States Design Patent

Oonuma et al.

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(54) **SEMICONDUCTOR TESTING MACHINE**

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(**) Term: **14 Years**

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(22) Filed: **Apr. 26, 2010**

(30) **Foreign Application Priority Data**

Oct. 30, 2009 (JP) 2009-025480

(51) **LOC (9) Cl.** **10-04**
(52) **U.S. Cl.** **D10/75**
(58) **Field of Classification Search** D10/75; 324/72.5, 750.03, 750.07, 750.08, 750.25, 324/756.02, 756.04, 762.01, 762.04, 762.05; 365/201; 439/70, 259, 260, 265; 702/120; 714/E11.001, E11.155, 719, 721, 724, 738
See application file for complete search history.

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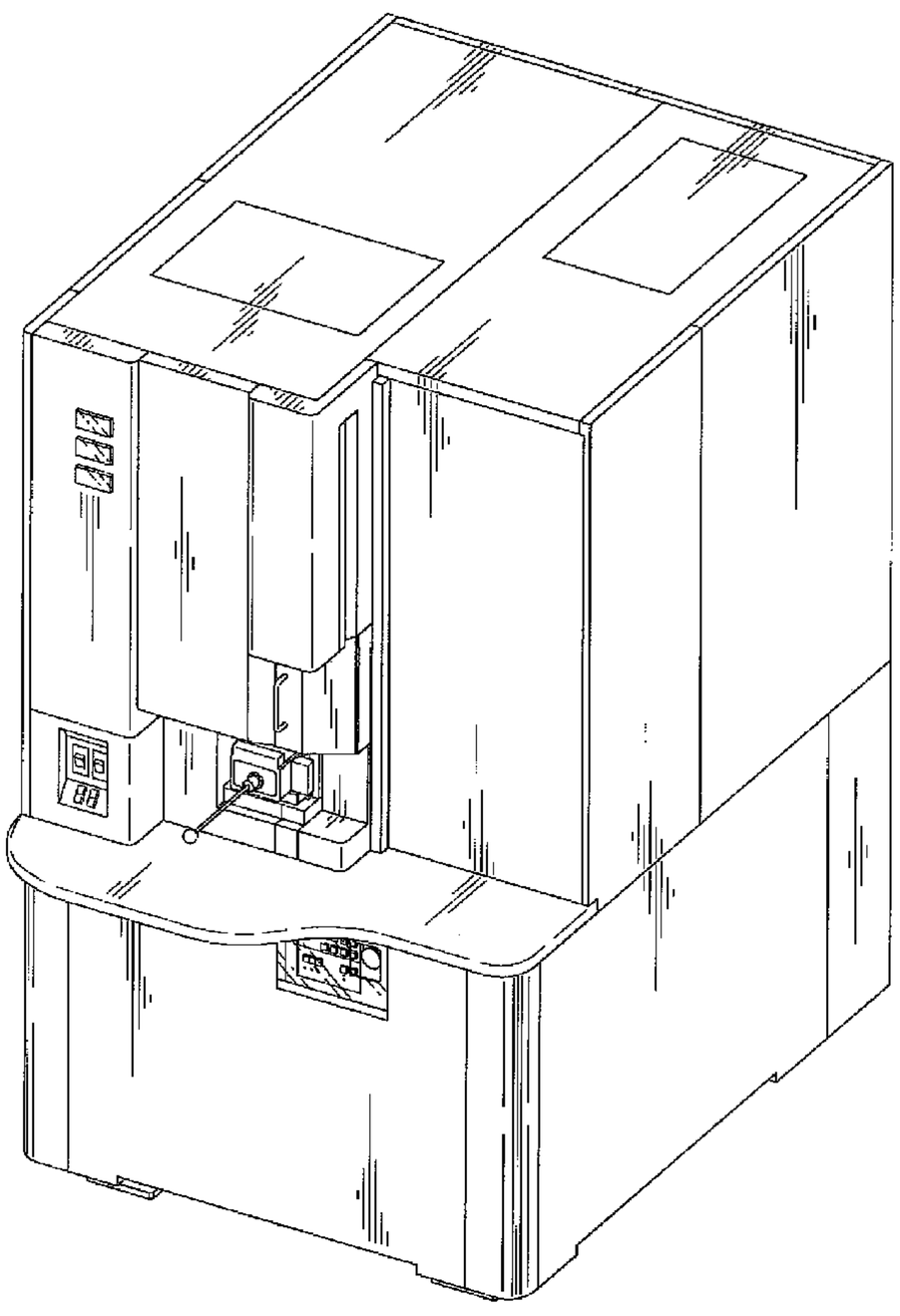
(57) **CLAIM**

The ornamental design for a semiconductor testing machine, as shown.

DESCRIPTION

FIG. **1** is a front, top and right side perspective view of a semiconductor testing machine showing our new design;
FIG. **2** is a front elevational view thereof;
FIG. **3** is a rear elevational view thereof;
FIG. **4** is a top plan view thereof;
FIG. **5** is a bottom plan view thereof;
FIG. **6** is a right side elevational view thereof; and,
FIG. **7** is a left side elevational view thereof.

1 Claim, 7 Drawing Sheets



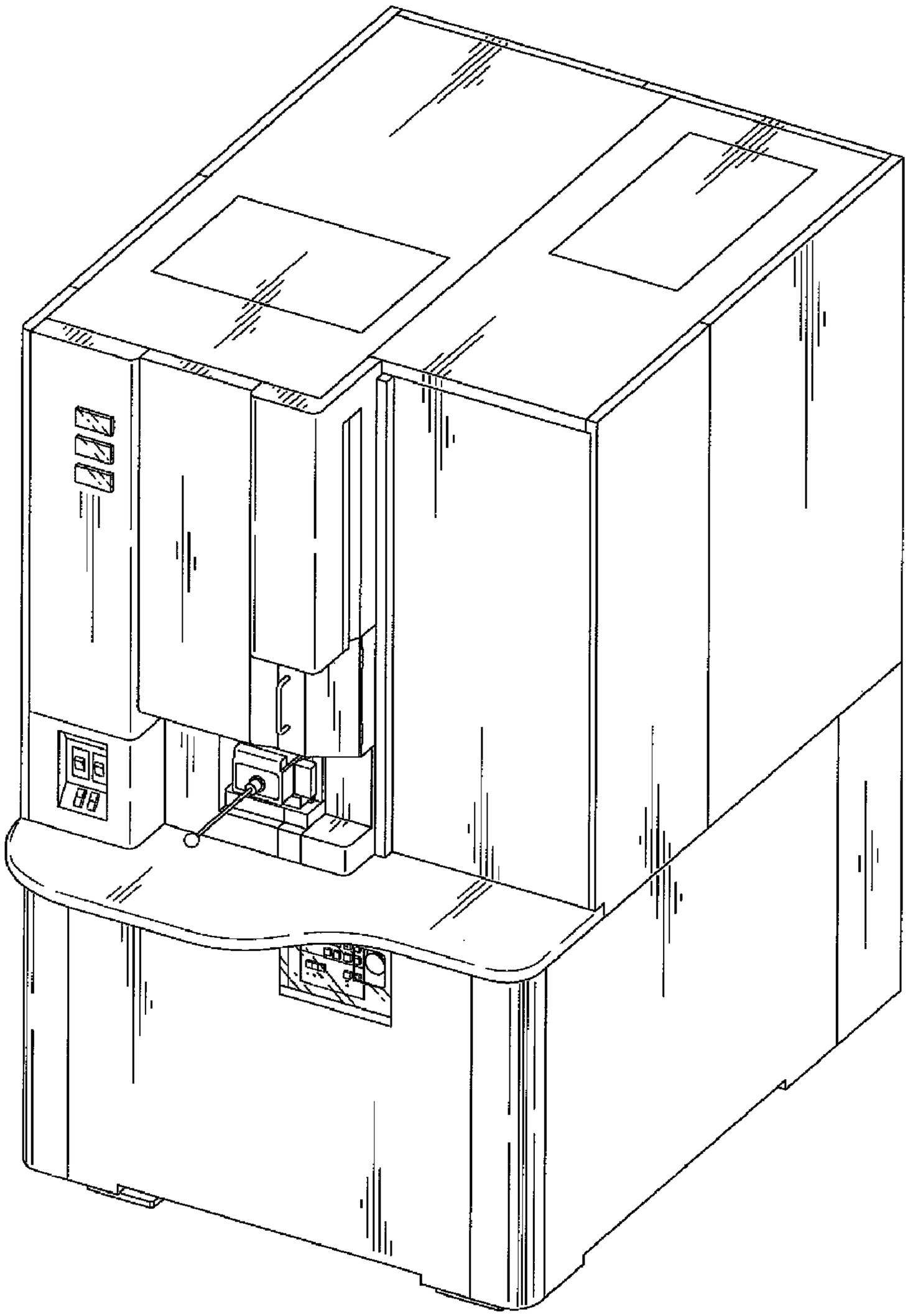


FIG. 1

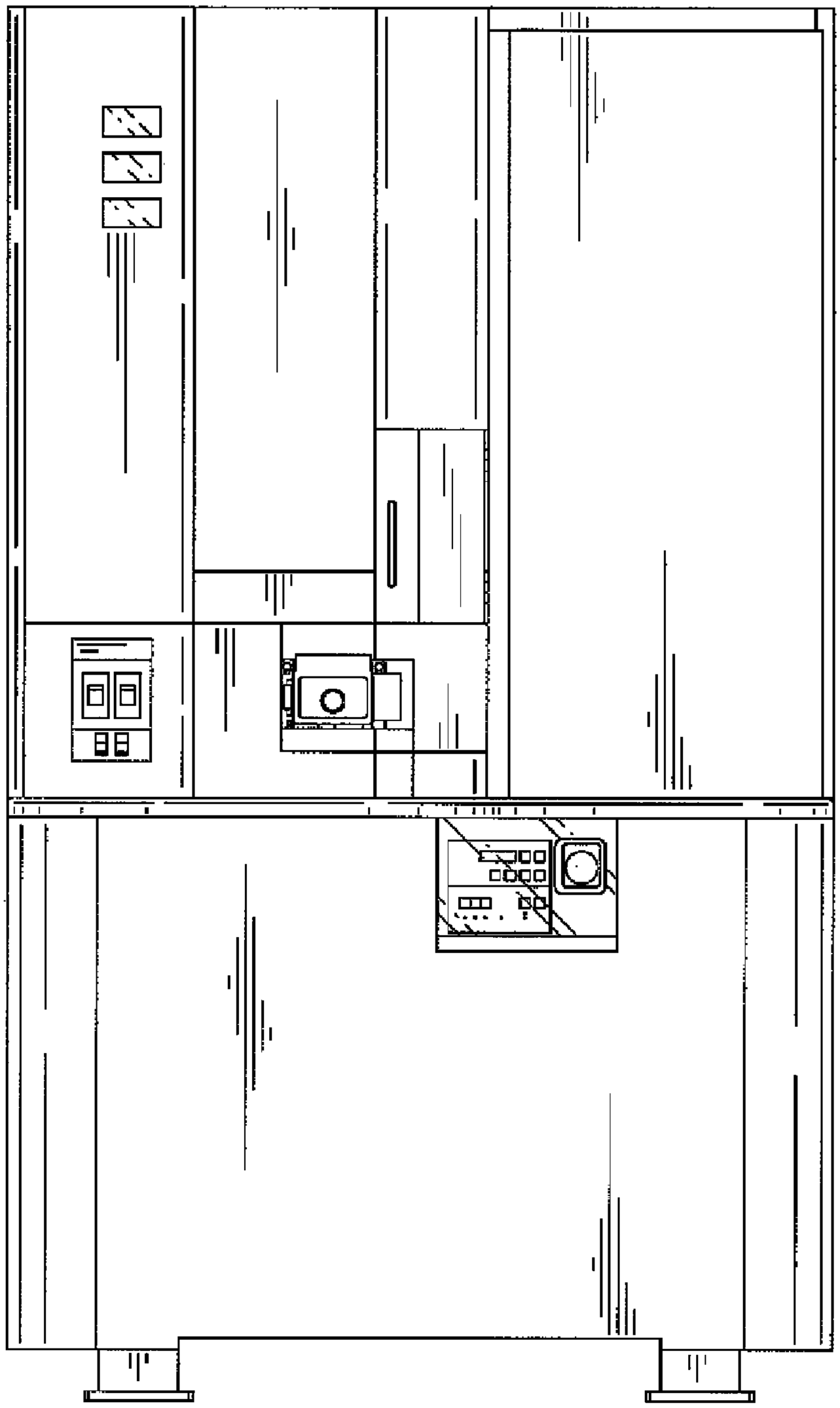


FIG. 2

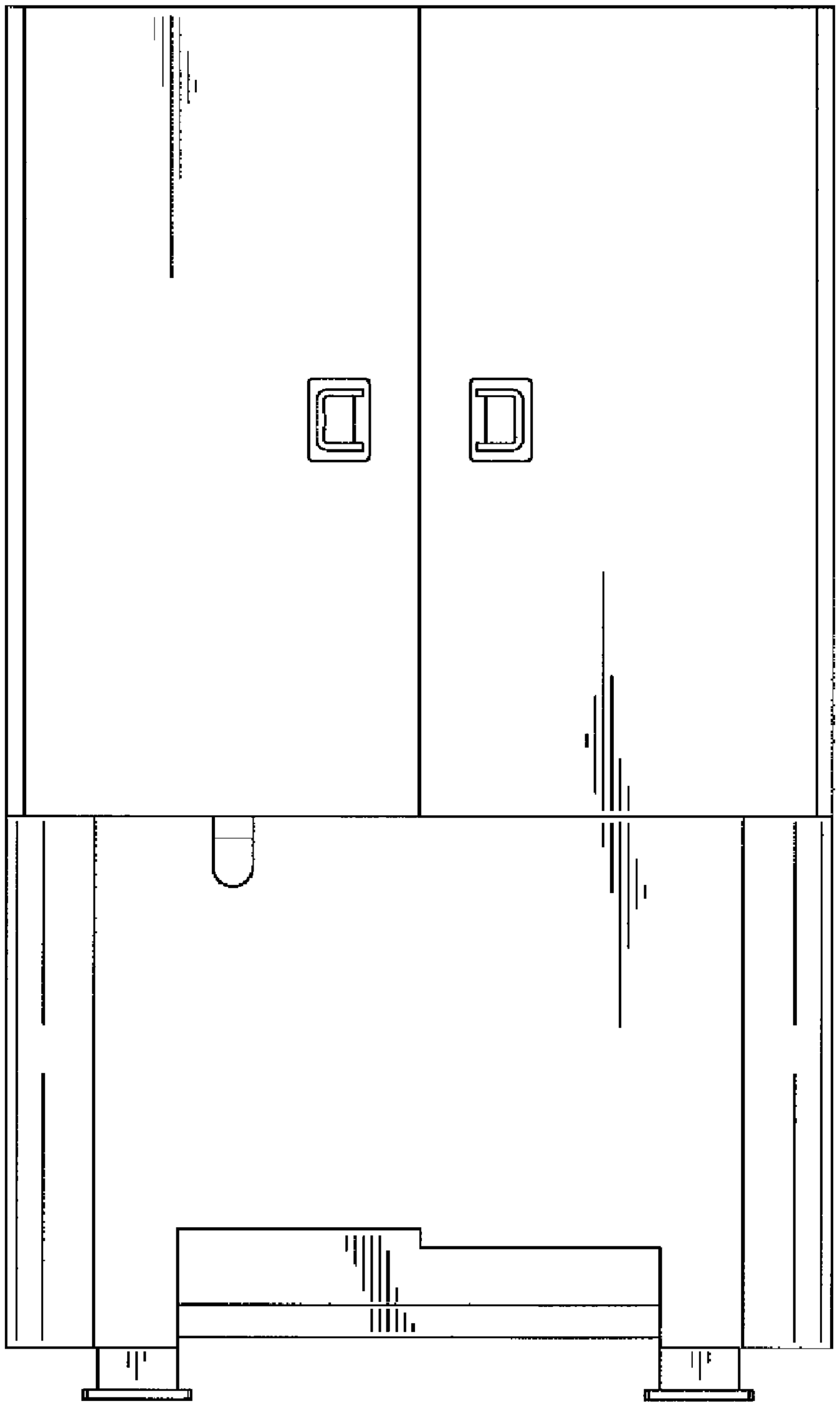


FIG. 3

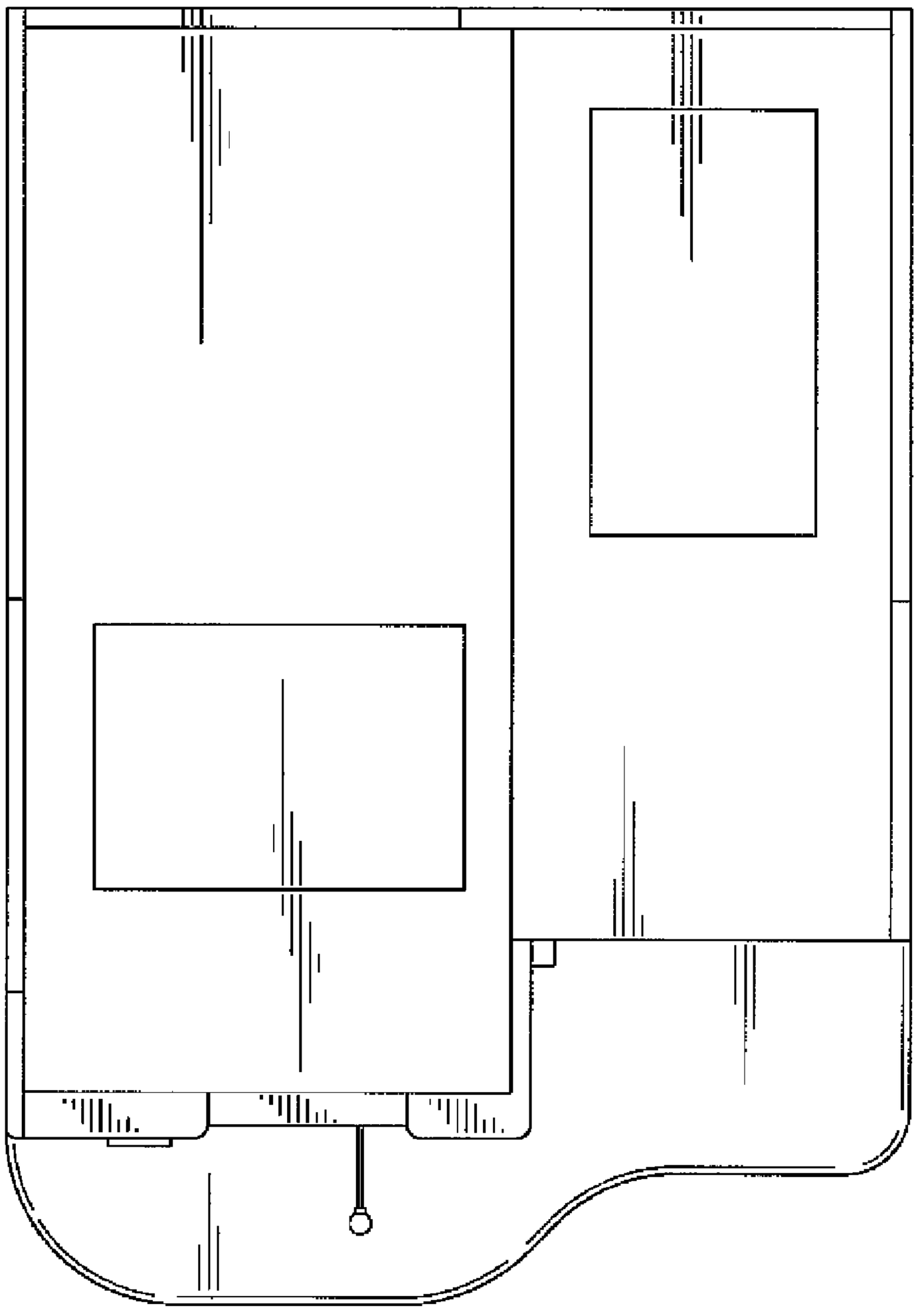


FIG. 4

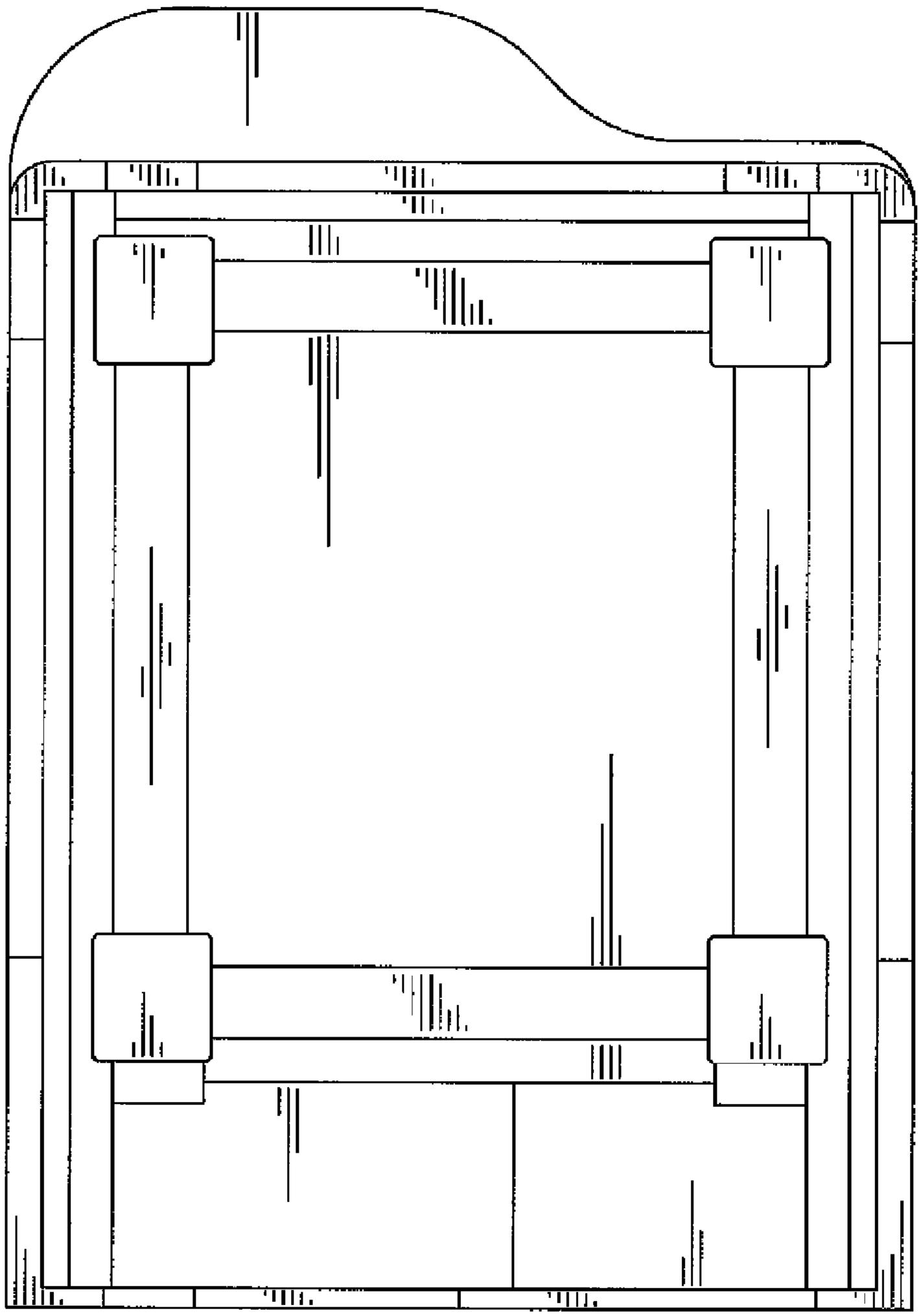


FIG. 5

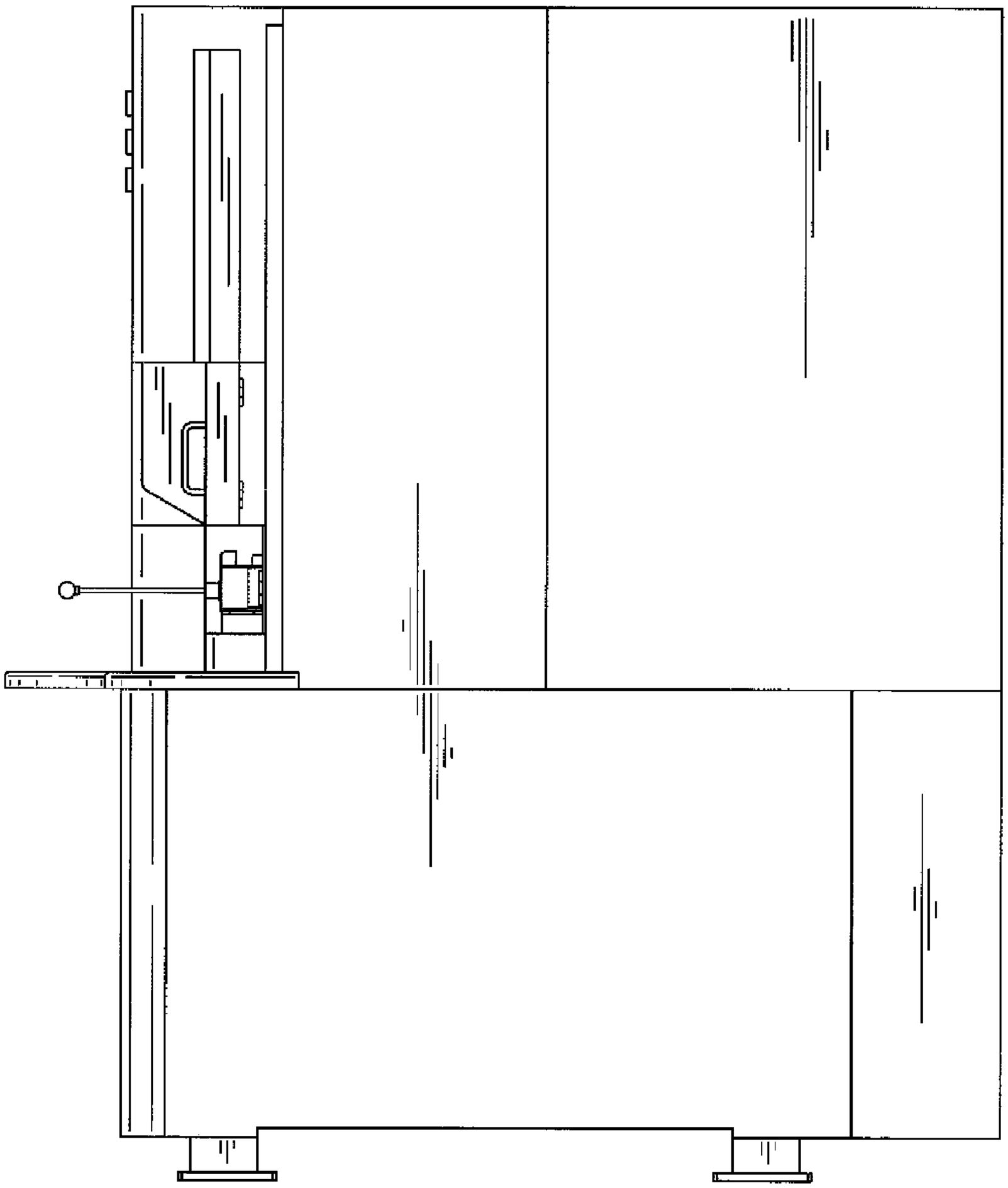


FIG. 6

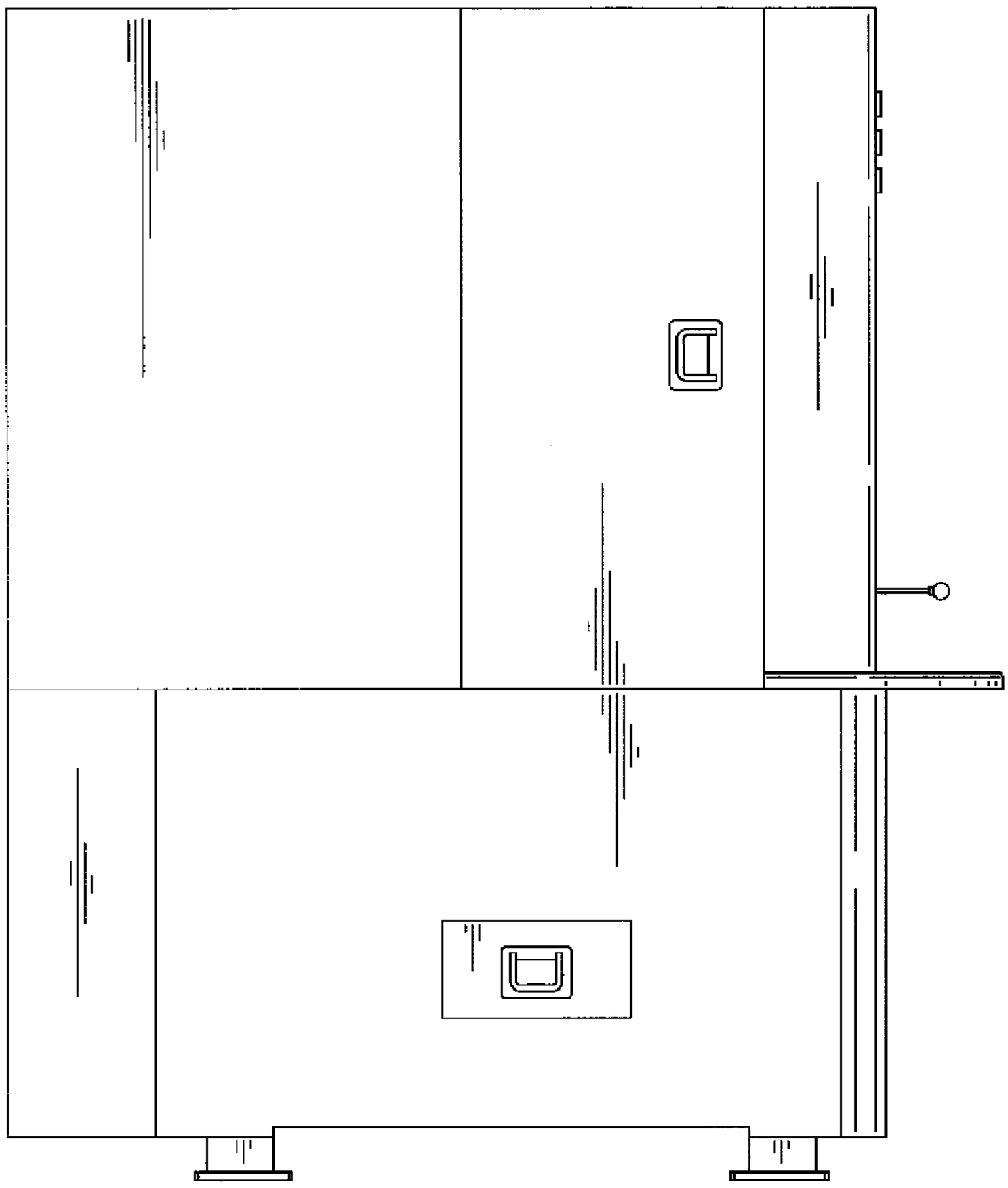


FIG. 7